## Main Options of A12 Prober



#### RFID/ FOUP ID Reader

- OCR wafer ID reader (Top / Bottom)
- 3 Buffer trays for wafer storage
- Loader mini-environment
- Automatic probe card changer
- Chuck: High/Low/Normal temperature
- Real time map data
- One touch contact probing
- PMAI: Probe Mark Auto-Inspection
- PLV: Prober Log Viewer
- RCS: Remote Control System
- DUT Editor & Recipe Editor

# SEMISHARE-A12

Auto-High Performance™ Patent:201910551106.3

## **Specifications of A12 Prober**

Main body	X axis	Accuracy : ≤±2µm
		Resolution: 0.02µm
	Y axis	Probing area: X ±170mm, Y -180 ~ +600mm.
		Maximum speed : 240mm/s
	Z axis	Accuracy : ≤±2µm
		Resolution: 0.02µm
		Maximum Z movement: 0 ~ 80mm
	0 axis	Rotation Range :±10°
		Resolution: 0.00001°
Loader	Cassette / Wafer Size	Φ200mm , Φ300mm
Monitor		15 inch High-resolution color LCD
Facility Requirement		Power :50/60Hz AC 208V, CDA: 0.4 to 0.8Mpa , Vacuum: -53 to -100Kpa
Dimensions & Weight		WxDxH: 1700 x 1820 x 1015 mm, 2200 KG (standard).



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The technology for automatic wafer probing and testing



## WAFER PROBING MACHINE





## SEMISHARE-A12 Wafer Probing Machine

The A12 prober is High-performance 300mm wafer probing machine, and main function of this equipment is to make an accurate contact between probe tips (probe card) and wafer pads in wafer sort /CP test.

SEMISHARE-A12 wafer prober provides a low cost, high throughput, good mechanical stability and easy operation solution for different customers. A12 wafer prober can handle 8 & 12 inch standard wafer, and compatible with various types of ATE.

## Auto-High Performance<sup>™</sup> technologies

Auto-High Performance<sup>™</sup> provide a highly stable fully automatic wafer testing technology. Through the multi-reinforced stable structure of the automatic wafer probe table, the problem that the equipment is easy to shake and affect the test accuracy is solved, and the motion stability and precision of the probe table in the wafer test process are guaranteed.

Wafer Load Time Reduction: An improved method for notch and wafer ID

synchronous recognition.

High Strength and Low Barycenter Design :

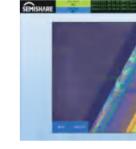
Support high pin count probe card, maximum Z force up to 200KG.

## Friendly Graphic User Interface



Wafer Edge Measurement



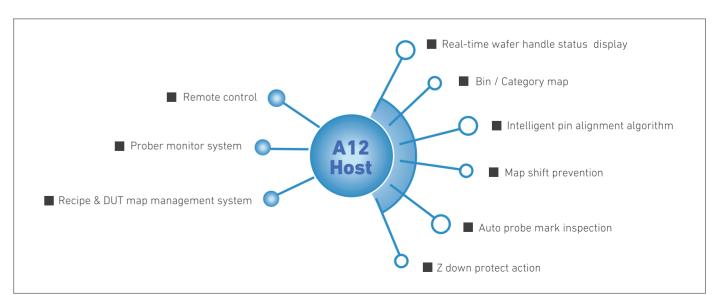


**PAD** Registration

Wafer ID Reading



## A12 Prober Features



#### **Recipe Parameter Settings**







#### Multi DUT Location Edit



#### Index & Z height



Real-time Wafer Map Data

